

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of)
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Masao IMAKI et al.) Group Art Unit: Unassigned
)
Application No.: Unassigned) Examiner: Unassigned
)
Filed: November 20, 2001)
)
For: WAVELENGTH MONITOR AND)
SEMICONDUCTOR LASER)
DEVICE)

PRELIMINARY AMENDMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

Prior to examination on the merits, please amend the above-identified application as follows. A replacement page 70 incorporating the claim change below is provided herewith for publication purposes.

IN THE CLAIMS:

Please replace claim 39 as follows:

39. (Amended) A method of monitoring the wavelength of a laser beam emitted by a semiconductor laser, comprising:

directing a laser beam through a cylindrical lens, thereby forming a uniaxially converged laser beam;

directing a first portion of the uniaxially converged laser beam through a wavelength filter to a first photodetector;

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directing a second portion of the uniaxially converged laser beam to a second photodetector;

determining a signal intensity ratio of a first signal intensity measured by the first photodiode to a second signal intensity measured by the second photodiode; and

comparing the signal intensity ratio to a reference signal intensity ratio that corresponds to a preset wavelength.

REMARKS

Claim 39 is amended to correct a typographical error, wherein "present" is changed to "preset". This amendment is not intended to narrow the scope of the affected claim element. Favorable action on the merits is respectfully requested.

A replacement page 70 incorporating the above-noted claim change is provided herewith for publication purposes.

Respectfully submitted,

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Attachment to Preliminary Amendment dated November 20, 2001

Marked-up Claim 39

39. (Amended) A method of monitoring the wavelength of a laser beam emitted by a semiconductor laser, comprising:

directing a laser beam through a cylindrical lens, thereby forming a uniaxially converged laser beam;

directing a first portion of the uniaxially converged laser beam through a wavelength filter to a first photodetector;

directing a second portion of the uniaxially converged laser beam to a second photodetector;

determining a signal intensity ratio of a first signal intensity measured by the first photodiode to a second signal intensity measured by the second photodiode; and

comparing the signal intensity ratio to a reference signal intensity ratio that corresponds to a [present] preset wavelength.

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detecting means for detecting the laser beam passed through the cylindrical lens; and

intensity changing means for changing the intensity of a portion of the laser beam depending upon the wavelength of the laser beam, the intensity changing means being disposed in an optical path between the semiconductor laser and the detecting means.

38. A semiconductor laser device according to claim 3, wherein the beam receiving face of the first photodetector and the beam receiving face of the second photodetector are placed on different planes from each other.

39. A method of monitoring the wavelength of a laser beam emitted by a semiconductor laser, comprising:

directing a laser beam through a cylindrical lens, thereby forming a uniaxially converged laser beam;

directing a first portion of the uniaxially converged laser beam through a wavelength filter to a first photodetector;

directing a second portion of the uniaxially converged laser beam to a second photodetector;

determining a signal intensity ratio of a first signal intensity measured by the first photodiode to a second signal intensity measured by the second photodiode; and

comparing the signal intensity ratio to a reference signal intensity ratio that corresponds to a preset wavelength.